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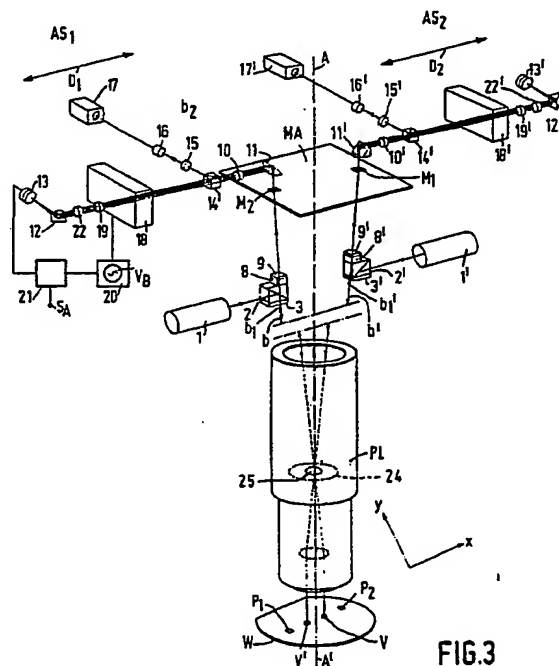
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(54) Apparatus for projecting a mask pattern on a substrate.

(57) An apparatus for projecting a mask pattern (MA) on a substrate (W) by means of a projection lens system (PL) is described, which apparatus comprises a device for aligning a substrate alignment mark (P_1 ; P_2) with respect to a mask alignment mark (M_1 ; M_2), the projection lens system (PL) forming part of the alignment device. A correction element (25) is arranged in this system (PL) to compensate for the fact that this system (PL) is not optimised for the wavelength of the alignment beam (b).



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EUROPEAN SEARCH REPORT

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EP 90 20 0925

DOCUMENTS CONSIDERED TO BE RELEVANT			
Category	Citation of document with indication, where appropriate, of relevant passages	Relevant to claim	CLASSIFICATION OF THE APPLICATION (Int. Cl.5)
D,A	EP-A-237109 (ASM LITHOGRAPHY) * pages 11 - 25; claim 10; figures * & US-A-4778275 ---	1, 3, 4, 7, 10 11, 13, 16-19	G03F9/00
A	DE-A-1904504 (WESTERN ELECTRIC) * pages 5 - 9; figures * ---	1, 3	
D,A	DE-A-2608176 (LENINGRADSKI INSTITUT TOTSCHNOJ MECHANIKI I OPTIKI ET AL.) * page 11, last 3 lines - page 12, figures 4-7 * -----	12	
			TECHNICAL FIELDS SEARCHED (Int. Cl.5)
			G03B
The present search report has been drawn up for all claims			
Place of search THE HAGUE		Date of completion of the search 15 JUNE 1990	Examiner HERYET C. D.
CATEGORY OF CITED DOCUMENTS X : particularly relevant if taken alone Y : particularly relevant if combined with another document of the same category A : technological background O : non-written disclosure P : intermediate document T : theory or principle underlying the invention E : earlier patent document, but published on, or after the filing date D : document cited in the application L : document cited for other reasons & : member of the same patent family, corresponding document			

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